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ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10004168	FILING DATE 10/30/2001	CLASS 438	SUBCLASS 4	GAU 2812	2825	EXAMINER N. T. 303
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**APPLICANTS: Ono Makoto; Iwata Hisafumi; Kirino Keiko;

**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 2000-334915 10/30/2000

P/G-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed 35 USC 119 conditions met		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO
Verified and Acknowledged Examiner's initials			16869P-037300US
TITLE : Inspection system and semiconductor device manufacturing method			
U.S. DEPT. OF COMM /PAT & TM-PTO-436L; Rev. 12-94			

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	
ISSUE FEE		Primary Examiner	
Amount Due	Date Paid	Total Claims	Print Claim for O.G
		DRAWING	
		Sheets Drwg.	Figs. Drwg.
		Print Fig.	
TERMINAL DISCLAIMER		Application Examiner	
PREPARED FOR ISSUE			
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